

BENCHTOP PLASMA SYSTEM

PE-200

27"

34"



THE PE-200 IS OUR INDUSTRIAL STRENGTH BENCH TOP SYSTEM AND SUPPLIED WITH AN OXYGEN SERVICE VACUUM PUMP.

THIS ROBUST, RELIABLE AND YET QUITE AFFORDABLE SYSTEM WAS DEVELOPED FOR THE BUSY 24/7 MANUFACTURING FIRM THAT CANNOT HAVE DOWNTIME.

OUR WELDED ALUMINUM VACUUM CHAMBER ENCLOSES A GENEROUS 500 SQUARE INCHES OF ACTIVE PLASMA PROCESSING SURFACE. SURFACE MODIFICATION WITH

PLASMA ETCH YIELDS INCREASED BOND STRENGTH AND CLEANLINESS OF MOST ANY SURFACE MATERIAL.

ETCHING IN OUR PLASMA SYSTEM RATHER THAN WITH CHEMICAL BATHS CAN ELIMINATE EXPENSIVE HAZARDOUS CHEMICAL WASTE. OUR SIMPLE TO USE, INTUITIVE TOUCH SCREEN INTERFACE CONTROLS EVERY ASPECT OF THE PLASMA PROCESS ENSURING REPEATABILITY.

WE WILL CUSTOM CONFIGURE THE CHAMBER AND ELECTRODE CONFIGURATION TO SUIT YOUR

PRODUCT OR PROCESS INCLUDING CUSTOM SIZED HORIZONTAL ELECTRODES, RIE (REACTIVE ION ETCH) AND SEMICONDUCTOR LEAD FRAME MAGAZINES. REST ASSURED THAT PLASMA ETCH WILL BE THERE FOR YOU AS LONG AS YOU OWN YOUR SYSTEM.

PLASMA ETCH
PROGRESS THROUGH INNOVATION

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STANDARD SYSTEM FEATURES

WELDED ALUMINUM VACUUM CHAMBER, 17" X 14" X 14"
3 HORIZONTAL PROCESSING ELECTRODE LEVELS; 13" X 13" ON 3" SPACING
300 WATT R.F. GENERATOR @ 13.56 MHZ | AUTOMATIC MATCHING NETWORK
ONE 200 SCCM MASS FLOW CONTROLLER | PIRANI VACUUM GAUGE 0-1 TORR
MICROPROCESSOR CONTROL SYSTEM W/TOUCH SCREEN INTERFACE
STORES UP TO 20 TWO STEP RECIPES | 29 CFM OXYGEN SERVICE VACUUM PUMP
3 MICRONS VACUUM PUMP OIL FILTRATION

OPTIONAL SYSTEM FEATURES

ELECTROSTATIC SHIELDING | PROCESS TEMPERATURE CONTROL
600 W RF GENERATOR @ 13.56MHZ | 600W AUTOMATIC MATCHING NETWORK
59 CFM VACUUM OXYGEN SERVICE VACUUM PUMP (3 PHASE)
AUTOMATIC 2 POINT N2 PURGE SYSTEM FOR VACUUM PUMP LONGEVITY
SIGNAL LIGHT TOWER | MKS AUTOMATIC THROTTLE VACUUM CONTROLLER
2 ADDITIONAL MASS FLOW CONTROLLERS (TOTAL OF 3)
SOFTWARE SELECTABLE 5 PROCESS GAS INPUT STEERING MATRIX
CONTROLLED RATE N2 CHAMBER PURGE
OIL MIST COALESCING FILTER ON VACUUM PUMP EXHAUST
CUSTOM CHAMBER SIZE AND CONFIGURATION
CUSTOM ELECTRODE SIZE AND CONFIGURATION
RIE (REACTIVE ION ELECTRODE) CONFIGURATION

FACILITY OPTIONAL

PACKED BED FUME SCRUBBER
COMPRESSED AIR DRYER FOR VACUUM PUMP PURGE GAS SUPPLY

SYSTEM SPECIFICATIONS

AC SERVICE 208 VAC, 50/60 HZ 30 AMPS; SINGLE OR THREE PHASE
SYSTEM WEIGHT (PLASMA CONSOLE/VACUUM PUMP) 350/180 LBS.
FOOTPRINT, PLASMA CONSOLE 36 " X 36" X 32"
FOOTPRINT, VACUUM PUMP 16 " X 32" X 20"

FACILITY REQUIREMENTS

AC SERVICE 120/208 FIVE WIRE 3 PHASE OR 208 FOUR WIRE SINGLE PHASE
CONDITIONED ENVIRONMENT AT LESS THAN 850 F NON-CONDENSING
COMPRESSED AIR SERVICE 80-100 PSI <0.5 CFM
REGULATED PROCESS GASES 15-30 PSI

CONTACT US TODAY

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